

APR 07 2003

Patent
Attorney's Docket No. 015290-426

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of)
William Frederick BOSCH) Group Art Unit: 1765
Application No.: 09/607,922) Examiner: L.T. Umez-Erondu
Filed: June 30, 2000) Confirmation No.: 9687
For: SEMICONDUCTOR PROCESSING)
EQUIPMENT HAVING IMPROVED)
PARTICLE PERFORMANCE)

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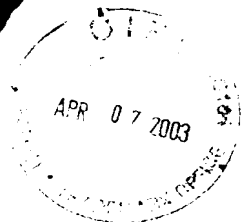
AMENDMENT TRANSMITTAL LETTER

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

Enclosed is an Amendment for the above-identified patent application.

- ☐ A Petition for Extension of Time is also enclosed.
- ☐ A Terminal Disclaimer and the ☐ \$55.00 (2814) ☐ \$110.00 (1814) fee due under 37 C.F.R. § 1.20(d) are also enclosed.
- ☐ Also enclosed is/are _____.
- ☐ Small entity status is hereby claimed.
- ☐ Applicant(s) request continued examination under 37 C.F.R. § 1.114 and enclose the ☐ \$375.00 (2801) ☐ \$750.00 (1801) fee due under 37 C.F.R. § 1.17(e).
- ☐ Applicant(s) previously submitted ___, on ___, for which continued examination is requested.
- ☐ Applicant(s) request suspension of action by the Office until at least ___, which does not exceed three months from the filing of this RCE, in accordance with 37 C.F.R. § 1.103(c). The required fee under 37 C.F.R. § 1.17(i) is enclosed.
- ☐ A Request for Entry and Consideration of Submission under 37 C.F.R. § 1.129(a) (1809/2809) is also enclosed.
- ☒ No additional claim fee is required.



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AMENDMENT

Assistant Commissioner for Patents
Washington, D.C. 20231

Sir:

In response to the Official Action dated January 6, 2003, please amend the above-captioned patent application as follows.

IN THE CLAIMS:

Please cancel Claim 35 without prejudice to or disclaimer of the subject matter contained therein, and replace Claims 1-4, 8-15, 19 and 36, as follows.

1. (Twice Amended) A method of processing semiconductor substrates and reducing particle contamination during processing of the substrates, the method comprising steps of:

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